CM-460 SERIES





The perrenial workhorse in the SIGNATONE product offering, the CM-460 Series of 6" semi-automatic analytical probe stations represents mature technology at its best. Based on our proven linear motor technology, which virtually eliminates accuracy and repeatability issues, the CM-460 will deliver years of worry-free performance where

and when you need it.



PERFORMANCE, QUALITY, VALUE

SIGNATONE®

Specifications

Wafer Stage

150mm XY linear motor drive mounted on 2" aircraft aluminum base

	CM-461-XX	CM-465-XX
X & Y Axis Resolution:	0.1µ	1µ
X & Y Axis Repeatability:	0.5 μ	1µ
X & Y Axis Accuracy:	1μ	3µ
Z Axis Resolution:	0.1µ	0.1µ
Z Axis Accuracy:	0.25µ	0.25µ

Programmable Z speed with Soft-Z edge-sense option

Positioner Platen

- 0.5" aluminum platen (steel optional) with 1" aluminum channel sub-platen brace
- Leadscrew-driven Z motion: 0.15" Contact/Separate, 1.75" height adjustment range with lock

Microscope Transports

- 2"x2" manual (-22) and programmable (-2M) transports with 4" pneumatic Z-lift
 - 10" X 6mm cross-roller bearings
 - 100+ pound load rating
- 4"X4" StereoZoom option with microscope tilt-back (-44)

Motion Control Features

- Local and Remote operation (RS-232C, GPIB, ActiveX)
- USB or Ethernet controller to prober communication to eliminate bus conflicts
- Joystick option with 2-axis joystick and optically-encoded thumbwheels for sub-μ control
- Integrated support for up to 4 Computer-Aided Positioners

System Software Features

- Single level user interface with icons and ToolTips
- 2-point software theta auto-alignment
- Programmable Z with Contact/Separate/Overdrive presets
- On-screen live video display with image capture/save
- Integrated Wafer Map and editor
 - Click to Move
 - Go To Row & Column navigation
 - · Local Step & Repeat debug mode
- Unlimited Save/Restore of prober setup files and wafer maps
- Color-coded wafer map with 256 user-defined binning colors
- Sub-Site probing capability with editor
- Learn Mode for saving program probe points
- Integrated thermal chuck control
- Point & Shoot, Drag & Drop, Measure Mode, Probe/Scope Tracking
- Microscope objective compensation
- Dual inker support (Inkers not included)
- Supports: LABView, Keithley KITE, Agilent VEE, ICS Metrics

Integrated Applications

- CV, IV, V_{th}, T_{ox},
- Lucas Labs Resistivity Measurement Suite
- RF/Microwave with optional calibration chuck



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